FORM PTO-1449 (REV.7-80) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

(Use several sheets if necessary)

ATTY. DOCKET NO. 500466.04

APPLICATION NO. 10/813,204
not yet assigned

INFORMATION DISCLOSURE STATEMENT

APPLICANT(S)

Kie Y Ahr

Kie Y Ahn and Leonard Forbes

FILING DATE
Concurrently herewith

GROUP ART UNIT 2879
not yet assigned

II S PATENT BOCIMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Mys	AA	3,665,241	05/23/72	Spindt et al.	313	351	
	AB	3,755,704	08/28/73	Spindt et al.	313	309	
	AC	3,812,559	05/28/74	Spindt et al.	29	25	
	AD	3,954,523	05/04/76	Magdo et al.	438	409	
	ΑE	4,016,017	04/05/77	Aboaf et al.	438	441	
	AF	4,266,233	05/05/81	Bertotti et al.	257	271	
	AG	4,652,467	03/24/87	Brinker et al.	427	246	
	ĄН	4,857,161	08/15/89	Borel et al.	445	24	
	Al	4,987,101	01/22/91	Kaanta et al.	438	619	
	LAJ_	5,103,288	04/07/92	Dakamoto et al.	257	758	
	AK	5,142,184	8/25/92	Kane	313	309	_
	AL	5,186,670	02/16/93	Doan et al.	445	24	
	AM	5,194,780	3/16/93	Meyer	315	169.3	
	AN	5,229,331	07/20/93	Doan et al.	437	228	
	AO	5,259,799	11/09/93	Doan et al.	445	24	
	ΑP	5,358,908	10/25/94	Reinbert et al.	438	20	
	AQ	5,372,973	12/13/94	Doan et al.	437	228	
	AR	5,430,300	07/04/95	Yue et al.	445	50	
	AS	5,458,518	10/17/95	Lee	445	24	
	ΑT	5,470,801	11/28/95	Kapoor et al.	438	471	
	ΑU	5,473,222	12/05/95	Theony et al.	315	169.1	
	ΑV	5,483,067	01/09/96	Fujii et al.	250	338.3	
	AW	5,529,524	06/25/96	Jones	445	24	
	AX	5,569,058	10/29/96	Gnade et al.	445	24	

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* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).

U.S. DEPARTMENT OF COMMERCE FORM PTO-1449 ATTY. DOCKET NO. APPLICATION NO. 10/8/3,20 (REV.7-80) PATENT AND TRADEMARK OFFICE 500466.04 not yet assigned APPLICANT(S) INFORMATION DISCLOSURE STATEMENT Kie Y Ahn and Leonard Forbes (Use several sheets if necessary) FILING DATE GROUP ART UNIT 2879 Concurrently herewith not yet assigned U.S. PATENT DOCUMENTS *EXAMINER DOCUMENT NUMBER DATE NAME **CLASS** SUBCLASS FILING DATE INITIAL IF APPROPRIATE 11/26/96 309 Huang 313

AZ	5,585,301	12/17/96	Lee et al.	437	60
ВА	5,597,444	01/28/97	Gilton	156	643
вв	5,653,619	08/05/97	Cloud et al.	445	24
 вс	5,663,608	09/02/97	Jones et al.	313	309
BD	5,684,356	11/04/97	Jeng et al.	445	70
ВЕ	5,712,534	1/27/98	Lee et al.	315	169.3
BF	5,793,154	8/11/98	Itoh et al.	313	308
BG	5,804,910	09/08/98	Tjaden et al.	313	310
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 ВІ	5,869,169	02/09/99	Jones	428	213
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 вк	6,028,322	02/22/00	Moradi	257	10
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ВМ	6,251,470	06/26/01	Forbes et al.	427	97
BN	6,255,156	07/03/01	Forbes et al.	438	235
ВО	6,277,765 B1	08/21/01	Cheng et al.	438	773
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	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANS YES	LATION NO
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Boswell, E.C. et al., "Polycrystalline Silicon Field Emitters," 8th International Vacuum Microelectronics Conference Technical Digest, pp. 181-186, 1996

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FORM PTO-144 (REV.7-80)	9	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 500466.04	application no. 10 813, 204 not yet assigned			
INF(ORM.	ATION DISCLOSURE STATEMENT	APPLICANT(S) Kie Y Ahn and Leonard Forbes				
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		OTHER PRIOR ART (Including	Author, Title, Date, Pertinent Pages, Etc.)			
Boswell, E.C. et al., "Polycrystalline silicon 1996			n field emitters," J Vac Sci Tec	hnol. B 14(3):1910-1913,			
	BU	Chalamala, Babu R. et al., "Fed Up with Fa					
	BV	Huang, W.N. et al., "Photoluminescence in etching," Semicond. Sci. Technol. 12:228-2.		ilms formed by chemical			
	вw	Huang, W.N. et al., "Properties of chemical sputtering," IEEE Hong Kong Electron Dev					
	вх	Huq, S.E. et al., "Comparative study of gate Vac. Sci. Technol. B 15(6):2855-2858, 1997	ed single crystal silicon and po				
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	BZ		g, pp. 367-370, 1996 ayer Structure of Polycrystalline Silicon," 9 th International				
	55	Vacuum Microelectronics Conference, St. F					
	CA	Kim, I.H. et al., "Fabrication of metal field <i>Technol. B 15</i> (2):468-471, 1997					
	СВ	Ku, T.K. et al., "Enhanced Electron Emission Emitter Arrays," <i>IEEE Electron Device Letter</i>	•	amond-Clad Silicon Field			
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		based on n-type porous silicon and on highle Crystalline Solids 198-200:973-976, 1996	y doped n-type porous polysili	con," Journal of Non-			
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	Cì	Stevenson, I.C. et al., "Production of SiO ₂ , I					
		of SiO with a Cold Cathode Source", Soc. of 1993	of Vac. Coaters, Proc. 36 th Ann	ual Tech. Conf., pp. 88-93,			
	СК	Uh, H.S. et al., "Enhanced Electron Emissic IEEE, pp. 713-716, 1997	on and Its Stability from Gated	Mo-polycide Field Emitters,"			
	CL	Uh, H.S. et al., "Fabrication and Characteria Arrays," 9th International Vacuum Microele					
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	Vaudaine, P. and Meyer, R., "Microtips Fluorescent Display," technical digest of IEDM 91, pp. 197 200, 1991			
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